

Notice of References Cited

Application/Control No.

09/909,847

Applicant(s)/Patent Under
Reexamination
IZADNEGAHDAR ET AL.

Examiner

A. Dexter Tugbang

Art Unit

3729

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-4,530,734	07-1985	Klima, Walter F.	216/99 x
	B	US-5,632,854	05-1997	Mirza et al.	438/53
	C	US-5,905,044	05-1999	Lee et al.	216/2 x
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP 2-36576	02-1990	Japan	Harada et al	29/25.35
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Chung et al, "Novel High-Performance Pressure Sensors Using Double SOI Structures", Solid State Sensors and Actuators, 1991, Digest of Technical Papers, 1991 International Conference on Transducers, June 1991, pages 676-681.
	V	Pak et al, "A New Method of Forming a Thin Single-Crystal Silicon Diaphragm using Merged Epitaxial Lateral Overgrowth Sensor Applications", IEEE Electron Device Letters, Nov. 1991, pages 614-616.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.